

Title (en)

SYSTEM AND METHOD FOR OPTICAL INSPECTION OF ELECTRONIC CIRCUITS

Title (de)

VORRICHTUNG UND VERFAHREN ZUR OPTISCHEN INSPEKTION VON ELEKTRONISCHEN SCHALTUNGEN

Title (fr)

SYSTEME ET PROCEDE D'INSPECTION OPTIQUE DE CIRCUITS ELECTRONIQUES

Publication

EP 2984913 A1 20160217 (FR)

Application

EP 14720669 A 20140409

Priority

- FR 1353275 A 20130411
- FR 2014050853 W 20140409

Abstract (en)

[origin: WO2014167248A1] The invention relates to an optical inspection system (10) for electronic circuit (Card) comprising sensors (C) of images of the electronic circuit, at least two supports (22, 24) on which are intended to rest two parts of the electronic circuit and a device (20) for modifying the position of each support, independently of one another.

IPC 8 full level

H05K 13/08 (2006.01); **G01N 21/956** (2006.01)

CPC (source: EP US)

G01N 21/95684 (2013.01 - EP US); **H05K 13/0815** (2018.07 - EP US); **G01N 2021/95638** (2013.01 - EP US)

Citation (search report)

See references of WO 2014167248A1

Citation (examination)

- US 2007218737 A1 20070920 - SUHARA SHINSUKE [JP]
- JP 2001153640 A 20010608 - ANRITSU CORP
- JP 2007311711 A 20071129 - ANRITSU CORP

Designated contracting state (EPC)

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Designated extension state (EPC)

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DOCDB simple family (publication)

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DOCDB simple family (application)

FR 2014050853 W 20140409; EP 14720669 A 20140409; FR 1353275 A 20130411; KR 20157030835 A 20140409; US 201414783491 A 20140409